

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re: PATENT APPLICATION of:

Inventor(s): JASPER et al.

Appln. No.: 09

519,875

Series Code ↑

Serial No. ↑

Group Art Unit 2851

Examiner: P. Kim

Atty. Dkt. P 257643

M#

P-0128.010-US

Client Ref

11/20/02

Filed: March 6, 2000

Title: OFF-AXIS LEVELLING LITHOGRAPHIC
PROJECTOR APPARATUSR
R C E
EDO NOT USE FOR PROVISIONAL,
DIVISIONAL, CIP OR DESIGN
APPLICATIONS, OR REEXAMINATION OF
PATENTSHon. Commissioner of Patents
Washington, D.C. 20231

Date: November 8, 2002

Sir:

REQUEST FOR CONTINUED EXAMINATION (RCE) UNDER RULE 114

Please continue the examination of this application.

PREREQUISITES

This application was filed on/after June 8, 1995, is not abandoned, and no court action has been filed, or if filed, it has been terminated.

An issue fee has not been paid (unless a petition under Rule 313(c)(2) is also being filed -- see item 4 below).

Prosecution has been closed as defined in Rule 114(b).**Reply to any outstanding action must be enclosed or previously filed.**

This application is entitled under Rule 114 to withdrawal of any outstanding finality or of any allowance plus a new action by the Examiner. Consideration on the merits of each submission (e.g., IDS, Amendment, new arguments, new evidence, but not appeal/reply briefs themselves) filed herewith is respectfully requested.

Please consider the following before the next Official Action:

1. Please enter do not enter the Amendment filed
2. The enclosed new Amendment
3. Consider the arguments in the appeal brief filed _____ and reply brief filed _____
4. The issue fee has been paid, but this RCE is based on Rule 313(c)(2). See enclosed petition
5. The enclosed Information Disclosure Statement

<input checked="" type="checkbox"/> IDS Letter	<input type="checkbox"/> Cited Appln	<input type="checkbox"/> Foreign Search Report/OA
<input checked="" type="checkbox"/> PTO-1449		<input type="checkbox"/> Cited Documents
6. Please suspend action under Rule 103(c) for a period of _____ months (3 mos. Max) for which charge the required \$130 fee (fee code 098) to our Deposit Account (see below).
7. Petition is hereby made to extend the original due date of August 8, 2002 to

(1 mo)	\$110/\$55
(2 mos)	\$400/\$200 + 920
(3 mos)	\$920/\$460

 cover the date this Request is filed. PLEASE CHARGE the requisite fee to our Deposit Account (see below)
8. PLEASE CHARGE the Rule 17(e) (RCE) filing fee of \$740 (lg. ent.) \$370 (sm. ent.) plus any deficiency and any other fee due now or later to our Deposit Account No. 03-3975 under Order No. 81468 / 257643

NOTE: Rule 17(e) filing fee Cannot be deferred!
NO CLAIMS FEE REQUIRED unless you are adding claims by box 2 Amendment in which case cover this with PAT-120.

11/12/2002 SMINASS1 00000056 09519875

C#

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920.00 CH

P.O. Box 10500
McLean, VA 22102(703) 905-2000
Atty/Sec: JH/tmtPillsbury Winthrop LLP
Intellectual Property Group

By Atty: Jean-Paul Hoffman Reg. No. 42663

Sig: *John P. Hoffman* Fax: (703) 905-2500
John P. Darling Tel: (703) 905-2094

NOTE: File this Request (plus enclosures, if any) in duplicate and with PTO receipt (PAT-103A)

11/12/2002 SMINASS1 00000056 09519875

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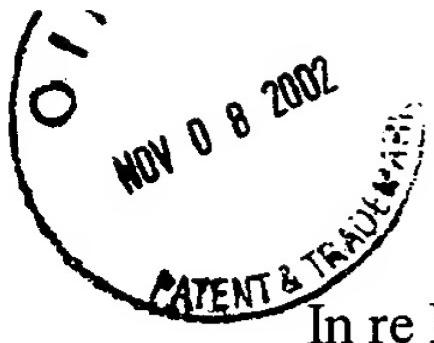
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11/12/2002



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION OF

JASPER et al.

Appln. No.: 09/519,875

Filed: March 6, 2000

Title: OFF-AXIS LEVELLING IN LITHOGRAPHIC PROJECTION APPARATUS

Confirmation No.: 8797

Group Art Unit: 2851

Examiner: P. KIM

#11(8)/C
11/20/02
OKON

November 8, 2002

* * * * *

AMENDMENT FILED WITH REQUEST FOR CONTINUED EXAMINATION

UNDER 37 C.F.R. § 1.114

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TECHNOLOGY CENTER 2000

Hon. Commissioner of Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated May 8, 2002, the period for reply being extended by a Petition for Three-Month Extension of Time and Request for Continued Examination filed herewith, please amend the above-identified application as follows:

IN THE CLAIMS:

Please enter amended claims 1-8 and 10-12 as follow:

1. (Thrice Amended) A lithographic projection apparatus comprising:
 - a first object table constructed and arranged to hold a mask;
 - a second, movable object table constructed and arranged to hold a substrate and having a physical reference surface fixed thereon;
 - 180.00 projection system constructed and arranged to image an irradiated portion of the mask onto a target portion of the substrate;
 - a positioning system constructed and arranged to move said second object table between an exposure station, at which said projection system can image said mask portion onto said substrate, and a measurement station;

11/20/2002 TOKEN

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